## **Supporting information**

## Direct Nanopatterning of Polymer/Silver Nanocubes Using Low Energy Electron Beam Irradiations

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Figure S1. SEM images recorded on (left) the nanospheres and (right) the micro-triangles. Scale bar:  $2 \ \mu m$ .



**Figure S2.** SEM image recorded on a nanocube after an excess in e-beam irradiation showing the formation of nanospheres (indicated in bright arrows) around the nanocube as a consequence to the surface diffusion of silver on the silicon substrate. Scale bar: 200 nm.



**Figure S3. False colored SEM images of various structures that can be created by local etching of silver nanostructures using e-beam.** a-d) three facets of a dice, d) silver nanocube cut in half, f) nanocube cut in four pieces, a) Smiley face and g) letter A. **Scale bar: 100 nm.** 



Figure S4. SEM image of a nanocube used to optimize the irradiation conditions. Scale bar: 200 nm.